A B S T R A C T

A laser unit (14) is arranged in an area of a floor surface (F), the width of which area is defined by maintenance areas, on both sides of an exposure-apparatus main body (12), inclusive. Furthermore, the exposure-apparatus main body (12) and the laser unit (14) are arranged on the floor surface (F) such that maintenance areas of the both overlap each other at least partially. Moreover, a C/D (16) is connected in-line with the front surface of the exposure-apparatus main body (12), and in the side of the exposure-apparatus main body (12), which side is in front of the optical axis of the projection optical system and which is connected with the C/D, a housing (22) is provided which has a delivery port (42) into and from which a mask container is loaded and unloaded by a ceiling-transport system that moves along a rail (Hr). Therefore, the laser unit is not further out into the maintenance areas than both side surfaces of the exposure-apparatus main body; the necessary area of the floor can be reduced, and the structure of a mask-transport system inside the exposure-apparatus main body can be prevented from becoming complicated.